

differential value and a reference value.

Fig. ¹⁴~~3~~ shows a relationship between impedance and time.

Fig. 15 shows a configuration of a high-frequency power supply system according to Embodiment 8 of the present invention.

Fig. 16 shows a configuration of a high-frequency power supply system according to Embodiment 9 of the present invention.

Fig. 17 shows a configuration of a high-frequency power supply system according to Embodiment 10 of the present invention.

Fig. 18 shows a configuration of an anomaly determiner according to Embodiment 10 of the present invention.

Fig. 19 shows a relationship between reflection coefficient and time.

Fig. 20 shows a configuration of a high-frequency power supply system according to Embodiment 11 of the present invention.

Fig. 21 shows a configuration of a high-frequency power supply system according to Embodiment 12 of the present invention.

Fig. 22 shows a configuration of a high-frequency power supply system according to Embodiment 13 of the present invention.

Fig. 23 shows a configuration of a conventional high-frequency power supply system.

Fig. 24 shows a relationship between reflection